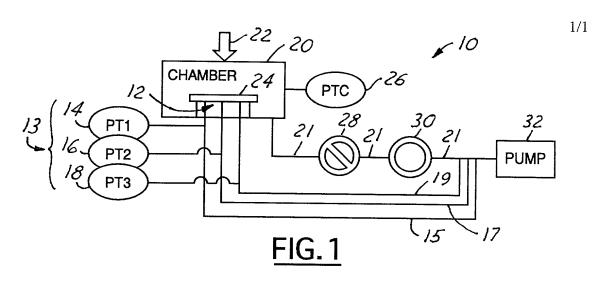
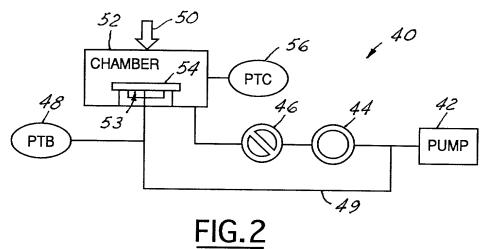
Inventor(s): Lai, et al Serial No.: To Be Assigned Filed: Herewith

For: In-Situ Measurement of Wafer Position on Lower Electrode

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78 83 PTB

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FIG. 3